

Fig 1. Schematic diagram illustrating the mechanism of ASD in this work.

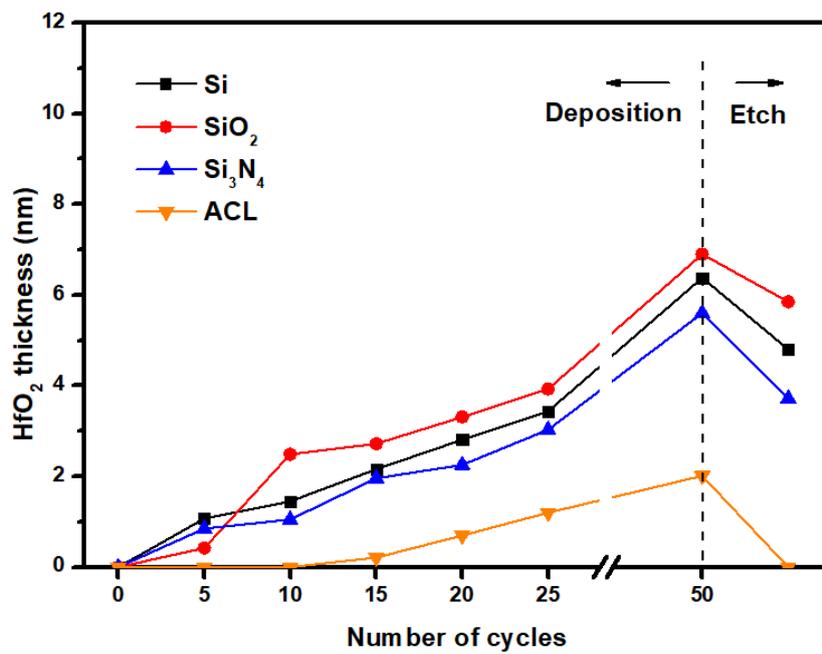


Fig 2. HfO₂ thickness on various substrates as a function of ALD cycles and after the etch step.